

ABSTRACT OF THE DISCLOSURE

A method of manufacturing a field emission device. In the method, emitters are formed using a lift-off process, and an isolation layer is formed between a sacrificial layer for patterning the emitters and emitter materials. The isolation layer prevents the sacrificial layer from reacting on the emitter materials to facilitate the lift-off process. Thus, the field emission device, which uniformly emits light having a high brightness, can be obtained.